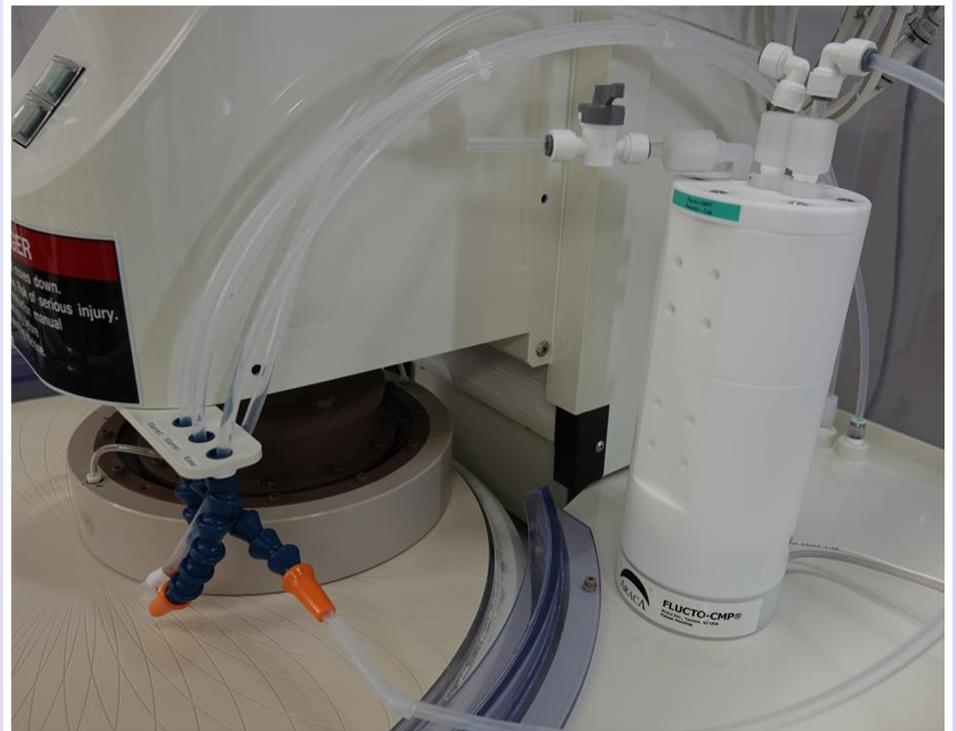
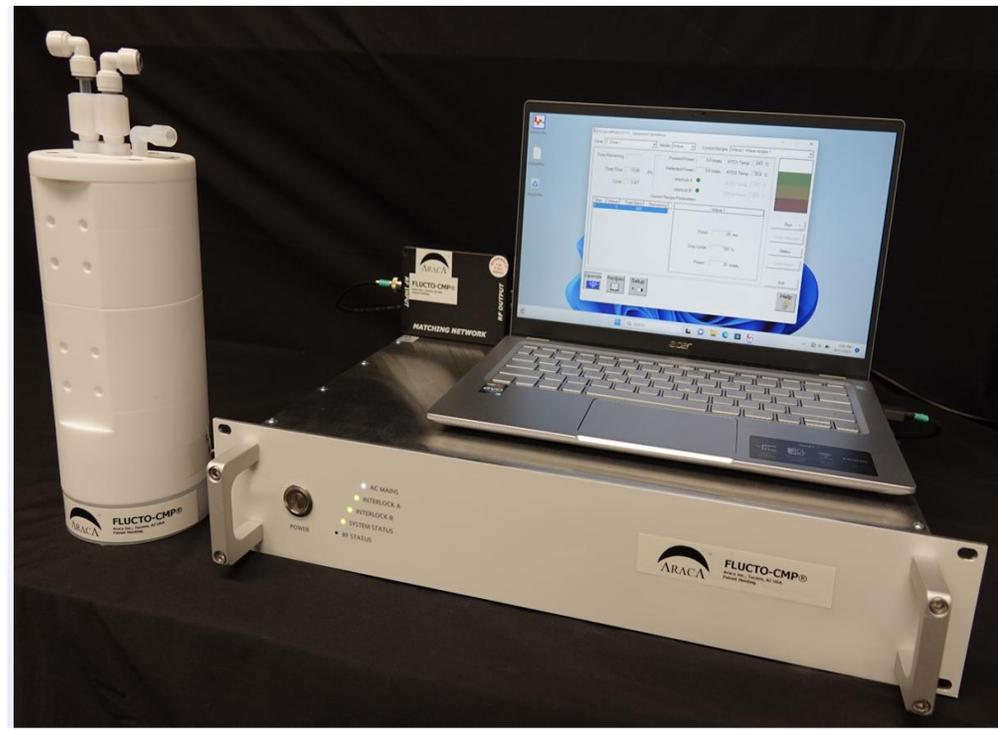




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Flucto-CMP® System for Defect Minimization, Device Yield Enhancement, Slurry Use Reduction and Environmental Stewardship



Details and Performance Highlights

| | |
|-------------------------|---|
| Manufacturer: | Reactor transducer, electronics and software made by ProSys (Campbell, CA USA). Made in Germany and the USA |
| Volume Capacity: | Modular reactor design allows for internal volumes of 150, 300 and 450 cc – Helps match flow rate to the reactor volume for improved mean residence time management. |
| Polishers: | Applied Material Mirra [®] , Reflexion [®] , Reflexion LK [®] and Reflexion LK Prime [®] Ebara F-REX [®] series SpeedFam-IPEC 372 [®] and 472 [®] Revasum 6DS-SP [®] and 6EC [®] |
| Wafers: | 150, 200 and 300 mm. |
| Applications: | Cu, W, Ti, TiN, Ta, TaN, Cobalt, SiC, Draco [®] Hardmask, and STI CMP. |
| Main Advantages: | At the same slurry flow rate, RR is boosted (10 to 100%) for “platen matching” or higher throughput. This method will still use less slurry due to shorter polish times. Slurry flow rate can be reduced proportionally to match POR RR. RR selectivity is increased dramatically with no adverse effects. Allows for pressure reduction (10 to 40%) with no loss in RR → Low stress polishing. For Cu, vibration is reduced by 60X and 5X, respectively. Defects are reduced by 10 to 30%. WIWRRNU remains unaffected. Flucto-CMP [®] is priced to give ROIs of less than 9 months. |
| ROI: | Flucto-CMP [®] is priced to give ROIs of less than 9 months. |
| Warranty: | One-year parts and labor. |

